## HIGHLIGHTS

$\square$ High pumping speed for all active gases
$\square$ Pumping speed for noble gases and methane
$\square$ Constant pumping speed for active gases in UHV-XHV
$\square$ No intrinsic pressure limitations
$\square$ Minimal power requirement during operations
$\square$ Extremely compact and light pump
$\square$ Reduced magnetic interference
$\square$ Able to measure pressure lower than $10^{-9}$ mbar
$\square$ Improvement of the ultimate vacuum in UHV-XHV systems
$\square$ Reduction of the footprint and weight of vacuum systems
$\square$ Scanning /transmission electron microscopes
$\square$ Surface science equipments
$\square$ Portable analysers vacuum instrumentations
$\square$ General purpose UHV systems
$\square$ Particle accelerators, synchrotron radiation sources and related equipments

The NEXTorr® ${ }^{\circledR}$ 2000-10 is an extremely compact pump which integrates sputter ion pump (SIP) and NEG pump technologies with larger pumping speed and capacity to sorb gases very effectively down to the XHV level. The getter cartridge is made of porous sintered getter disks stacked in a highly efficient gas trapping structure featuring pumping speed in excess of $2000 \mathrm{l} / \mathrm{s}\left(\mathrm{H}_{2}\right)$. The cartridge is integrated into a CF 100 flange containing heating elements for the getter activation. After the activation is carried out $\left(500^{\circ} \mathrm{C} \times 1 \mathrm{~h}\right)$, the NEG cartridge removes gases at room temperature without any need for electric power. On the other side of the same flange, an ion pump featuring $10 \mathrm{l} / \mathrm{s}$ for Ar and $20 \mathrm{l} / \mathrm{s}$ for $\mathrm{CH}_{4}$ is connected. Gas flows from the vacuum system to the ion pump through an optimized conductance. The optimized conductance and the special internal design of the ion pump allow the maximum exploitation of the ion pump sorption performance.
The NEXTorr D2000-10 is very suitable for particle accelerator and synchrotron applications where larger pumping speed and capacity in a very compact pump package are required to keep UHV conditions or below. It is very suitable also for analytical equipment like surface science systems (XPS, UPS, STM, and so on), MBE and vacuum deposition systems.


| Total pump weight (magnets included) | 6.8 kg |
| :--- | :--- |
| Total pump volume | 1.8 litre |
| Type of ion pump | Noble Diode |
| Operation Voltage lon Element | 5.0 kVdc |
| Operation Voltage NEG Element | 110 Vdc |

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| Initial pumping speed (1/s) | Gas | NEG activated | NEG saturated |
| :---: | :---: | :---: | :---: |
|  | $\mathrm{O}_{2}$ | 1700 | 9 |
|  | $\mathrm{H}_{2}$ | 2000 | 13 |
|  | CO | 1100 | 11 |
|  | $\mathrm{N}_{2}$ | 640 | 9 |
|  | $\mathrm{CH}_{4}$ | 32 | 17 |
|  | Argon ${ }^{1}$ | 10 (2.5) | 10 (2.5) |
| Sorption capacity (Torr•I) | Gas | Single run capacity ${ }^{2}$ | Total capacity ${ }^{3}$ |
|  | $\mathrm{O}_{2}$ | 300 | >10000 |
|  | $\mathrm{H}_{2}$ | 2250 | N/A ${ }^{4}$ |
|  | CO | 8 | >1600 |
|  | $\mathrm{N}_{2}$ | 2.8 | >220 |
| NEG section | Getter alloy type |  | St 172 |
|  | Alloy composition |  | ZrVFe |
|  | Getter mass (g) |  | 225 g |
|  | Getter surface ( $\mathrm{cm}^{2}$ ) |  | 1900 |
| ION section | Voltage applied |  | DC +5 kV |
|  | Number of Penning cells |  | 18 |
|  | Standard bake-out temperature |  | $150{ }^{\circ} \mathrm{C}$ |

1 Measured at $3 \times 10^{-6}$ Torr. Unsaturated pump (saturated pump).
2 Capacity values with the NEG element at room temperature, corresponding to a drop of the pumping speed to $10 \%$ of its initial value.
3 Total capacity values for each single gas obtained after many reactivations (getter fully consumed). Capacity values for the various gases are not additive (a getter fully reacted with one gas specie will not sorb another gas).
4 After the getter element has reached its room temperature $\mathrm{H}_{2}$ capacity ( $2250 \mathrm{Torr} \cdot \mathrm{l}$ ) it can be "regenerated". The regeneration process extracts the $\mathrm{H}_{2}$ stored in the getter. After being regenerated, the pump can start pumping $\mathrm{H}_{2}$ again

## Ordering Information

| Product | Product description | Code |
| :--- | :---: | :---: |
| NEXTorr PUMP | NEXTorr D 2000-10 | $5 \mathrm{H0181}$ |
| Pump power supply | NEXTorr PS NIOPS-06 | 3 B0440 |
| Power supply cables | NEXTorr KIT OF CABLES-04-06 | 3 B0416 |
| Power supply input cable | NIOPS INPUT CABLE | $3 B 0398$ |
| Output cable ION element | NIOPSO4-06-OUTPUT CABLE ION-3MT | $3 B 0418$ |
| Output cable NEG element | NIOPS04-06-OUTPUT CABLE NEG-3MT | $3 B 0419$ |

The NEXTorr ${ }^{\circledR}$ product line incorporates and exploits the patented concept of a combined pumping system comprising a getter pump and an ion pump, and have global Intellectual Property Rights coverage with patents already granted in the US $(8,287,247)$, Europe $(2,409,034)$, Japan $(5,372,239)$, China (102356236).

D 2000-10

The SAES Group manufacturing companies are ISO9001 certified, the Asian and Italian companies are also ISO14001 certified. Full information about our certifications for each company of the Group is available on our website at: www.saesgroup.com
D.VS.117.2.16

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